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PATENT APPLICATION

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of

Docket No: Q67319

Tsutomu SHOKI, et al.

Appln. No.: 09/987,990

Group Art Unit: 1756

Confirmation No.: 8044

Examiner: ROSASCO, STEPHEN D

Filed: November 16, 2001

For: SUBSTRATE WITH MULTILAYER FILM, REFLECTION TYPE MASK BLANK FOR EXPOSURE, REFLECTION TYPE MASK FOR EXPOSURE AND PRODUCTION METHOD THEREOF AS WELL AS PRODUCTION METHOD OF SEMICONDUCTOR DEVICE

**PETITION FOR EXTENSION OF TIME UNDER 37 C.F.R. § 1.136**

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Sir:

Pursuant to 37 C.F.R. § 1.136, Applicant hereby petitions for an extension of time of one month(s), extending the time for responding to the Office Action of July 15, 2003 to November 15, 2003.

A check for the statutory fee of \$110.00 is attached. The USPTO is directed and authorized to charge all required fees, except for the Issue Fee and the Publication Fee, to Deposit Account No. 19-4880. Please also credit any overpayments to said Deposit Account. A duplicate copy of this sheet is enclosed.

Respectfully submitted,

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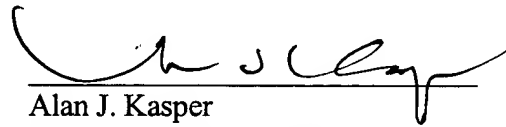
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WASHINGTON OFFICE

**23373**

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Date: November 14, 2003